ABSTRACT OF THE DISCLOSURE

A method of measuring the displacement of the optical axis of an optical microscope having an illumination optical system and a projection optical system having a step of irradiating the evaluation mark having diffraction grating patterns formed on a substrate with illumination light by way of the illumination optical system and observing the evaluation mark by way of the projection optical system to obtain the brightness of the evaluation mark, and a step of measuring the displacement of the optical axis on the basis of the relationship between the brightness of the image of the evaluation mark and the direction of the diffraction grating patterns of the evaluation mark.